## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

AUG 1 8 2003

In re Patent Application of

Shunpei YAMAZAKI et al.

Serial No. 09/932,935

Filed: August 21, 2001

For: LASER APPARATUS, LASER

ANNEALING METHOD, AND

MANUFACTURING METHOD OF A

SEMICONDUCTOR DEVICE

Art Unit: 2812

Examiner: V. Simkovic

## **CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with The United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231, on 8.15.2003

Adele M. Stamper

## **AMENDMENT**

Commissioner for Patents Washington, DC 20231

Sir:

In response to the Official Action dated April 15, 2003, please consider the following amendments and remarks in connection with the above-identified application.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 10 of this paper.

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TECHNOLOGY CENTER 2800

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